# **EAST Search History**

			<del> </del>		1	<del> </del>
Ref #	Hits	Search Query	DBs	Default Operat or	Plural s	Time Stamp
L1	1755	((strontium near3 ruthenium) near3 oxide) or (strontium ruthenate) or ("srruo.sub.3")	US-PGPU B; USPAT; USOCR; EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:25
L2	92	I1 and (bismuth oxide or "bi.sub.2 o.sub.3")	US-PGPU B; USPAT; USOCR; EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:07
L3	76	I2 and (target or sintered body or sputter\$3)	US-PGPU B; USPAT; USOCR; EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:19
L4	12	"srruo.sub.3" and "bi.sub.2 o.sub.3" and (target or sintered body or sputter\$3)	US-PGPU B; USPAT; USOCR; EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:28
<b>L</b> 5	. 19	"srruo.sub.3" and "bi.sub.2 o.sub.3"	US-PGPU B; USPAT; USOCR; EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:29

## **EAST Search History**

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L6	7	I5 not I4	US-PGPU B; USPAT; USOCR; EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:28
L7	0	"srruo.sub.3" and "bi.sub.2 o.sub.3"	EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:29
L8	Ö	"srruo.sub.3"	EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:30
L9	0	(srru\$2) and (bismuth oxide)	EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:31
L10	102	(srru\$2)	EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:31
L11	10	l10 and (target or sintered body or sputter\$3)	EPO; JPO; DERWEN T	ADJ	OFF	2007/01/20 13:32

## INTERNATIONAL SEARCH REPORT

Internal application No.
PCT/JP03/07483

A. CLASSIFICATION OF SUBJECT MATTER Int.Cl <sup>7</sup> C23C14/34, C04B35/01, H01L27/105, 21/285					
According to	According to International Patent Classification (IPC) or to both national classification and IPC				
	S SEARCHED		•		
Minimum d Int.	ocumentation searched (classification system followed C1 <sup>7</sup> C23C14/00-14/58, C04B35/01	by classification symbols) , H01L27/105, 21/285			
Jitsı Kokai	i Jitsuyo Shinan Koho 1971-2003	Toroku Jitsuyo Shinan Koh Jitsuyo Shinan Toroku Koh	0 1994–2003 0 1996–2003		
Electronic d WPI/	lata base consulted during the international search (nam 'L[(C23C-014/34 or C04B-035/00)	e of data base and, where practicable, sear and strontium (w) ruthen US 6843975	rch terms used) Lium]		
		05 6017117			
C. DOCU	MENTS CONSIDERED TO BE RELEVANT	<u></u>			
Category*	Citation of document, with indication, where ap	propriate, of the relevant passages	Relevant to claim No.		
X Y	WO 02/051769 A1 (NIXXO MATER 04 July, 2002 (04.07.02), Claims 1 to 6; technical fiel & JP 2002-193668 A Claims; Par. Nos. [0001], [00	1-3,6-8 4,5,9-14			
Y	JP 2000-247739 A (Vacuum Met 12 September, 2000 (12.09.00) Par. Nos. [0003], [0008], [00 (Family: none)	4,5,9-14			
A JP 6-56503 A (Showa Denko Ka 01 March, 1994 (01.03.94), Full description (Family: none)		bushiki Kaisha),	1-14		
X Furth	er documents are listed in the continuation of Box C.	See patent family annex.			
"A" docum	considered to be of particular relevance understand the principle or theory underlying the invention				
"L" docum cited to	nent which may throw doubts on priority claim(s) or which is no establish the publication date of another citation or other I reason (as specified)	considered novel or cannot be considered step when the document is taken along document of particular relevance; the considered to involve an inventive step.	red to involve an inventive claimed invention cannot be		
"O" docum	ent referring to an oral disclosure, use, exhibition or other	combined with one or more other such combination being obvious to a person	documents, such a skilled in the art		
document published prior to the international filing date but later than the priority date claimed  Date of the actual completion of the international search  Date of mailing of the international search					
16 September, 2003 (16.09.03) 07 October, 2003 (07.10.03)					
Name and n	nailing address of the ISA/ anese Patent Office	Authorized officer			
Facsimile N	lo.	Telephone No.			

### INTERNATIONAL SEARCH REPORT

Internation No.
PCT/JP03/07483

<del>-`</del>	tion). DOCUMENTS CONSIDERED TO BE RELEVANT	
Category*	Citation of document, with indication, where appropriate, of the relevant passages	
<b>A</b>	JP 2002-211978 A (Hitachi Metals, Ltd.), 31 July, 2002 (31.07.02), Full description (Family: none)	1-14
<b>A</b>	Written and edited by Yoshio TSUDA, "Denki Dendosei Sankabutsu", Enlarged edition No.3, Shokabo, 25 July, 1987 (25.07.87), page 9	1-14
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#### INTERNATIONAL PRELIMINARY EXAMINATION REPORT

Internat pplication No.
PCT/JP 03/07483

V.	Reasoned statement under Article 35(2) with regard to novelty, inventive step or industrial applicability;	;
1	citations and explanations supporting such statement	

1.	Statement			
	Novelty (N)	Claims	1-3, 6-8, 11, 14	YES
		Claims		NO
	Inventive step (IS)	Claims	1-3, 6-8, 11, 14	YES
		Claims		NO
	Industrial applicability (IA)	Claims	1-3, 6-8, 11, 14	YES
		Claims		NO

### 2. Citations and explanations

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Document 1: WO 02/051769 A1 (Nikko Materials Co., Ltd.),

04 July 2002, claims 1-6, field of the

invention, example 1 and table 1

Document 2: JP 2000-247739 A (Vacuum Metallurgical Co.,

Ltd.), 12 September 2000, paragraphs 3, 8,

12 and 14

Claims 1-3, 6-8, 11 and 14

The inventions that are set forth in claims 1-3, 6-8, 11 and 14 do not involve an inventive step in the light of document 1 and document 2 cited in the international search report.

Document 1 cited in the international search report discloses  $SrRuO_3$  oxide sintered compacts and spattering targets, which have a relative density of 95% or more and a specific resistance of approximately 260  $\mu\Omega$ cm (that is to say, document 1 had previously disclosed  $SrRuO_3$  oxide sintered compacts and spattering targets which have a relative density and a specific resistance similar to the relative densities and specific resistances that are specified in the claims of the present application, even without the addition of  $Bi_2O_3$ ).

Document 2 cited in the international search report discloses the feature of adding between 0.001-0.500 mol of

X

Bi<sub>2</sub>O<sub>3</sub> in order to increase the density when producing a SrRuO<sub>3</sub> sputtering target.

In the light of the abovementioned disclosures, it would be easy for a person skilled in the art to add  $Bi_2O_3$  to the  $SrRuO_3$  oxide sintered compacts and spattering targets that are disclosed in document 1, which have a relative density of 95% or more and a specific resistance of approximately 260  $\mu\Omega$ cm, in order to further increase the density thereof, and to adjust the load of  $Bi_2O_3$  so that it fulfills the relationship 0.5 mol < the load of  $Bi_2O_3 \le 1.0$  mol.

Furthermore, document 2 indicates that the load of Bi<sub>2</sub>O<sub>3</sub> is between 0.001-0.500 mol, and that the electrical conductivity of the invention deteriorates if the load of Bi<sub>2</sub>O<sub>3</sub> exceeds 0.5 mol (paragraph [0007]). Meanwhile, the specific resistances of the inventions that are set forth in the present application deteriorate if the load of Bi<sub>2</sub>O<sub>3</sub> exceeds 0.5 mol, as can be confirmed from the disclosures of the present application (fig. 1). Therefore, the present application merely confirms the technical content that is disclosed in document 2 (wherein the electrical conductivity of the invention deteriorates if the load of Bi<sub>2</sub>O<sub>3</sub> exceeds 0.5 mol). In addition, there is no significant effect that results from a configuration wherein the load of Bi<sub>2</sub>O<sub>3</sub> exceeds 0.5 mol.